

<b>Notice of References Cited</b>	Application/Control No. 10/522,533		Applicant(s)/Patent Under Reexamination MESCHKE, FRANK	
	Examiner ELIZABETH A. BURKHART		Art Unit 1792	Page 1 of 1

#### U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
*	A	US-6,579,833	06-2003	McNallan et al.	508/100
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
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	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

#### FOREIGN PATENT DOCUMENTS

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#### NON-PATENT DOCUMENTS

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	U	Matsui et al, Three-dimensional nanostructure fabrication by focused-ion-beam chemical vapor deposition, J. Vac. Sci. Technol. B 18(6), Nov/Dec 2000, p. 3181-3184.
	V	Kusunoki et al, Aligned carbon nanotube film self-organized on a SiC wafer, Jpn. J. Appl. Phys. Vol. 37 (1998), p. L605-L606.
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	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.